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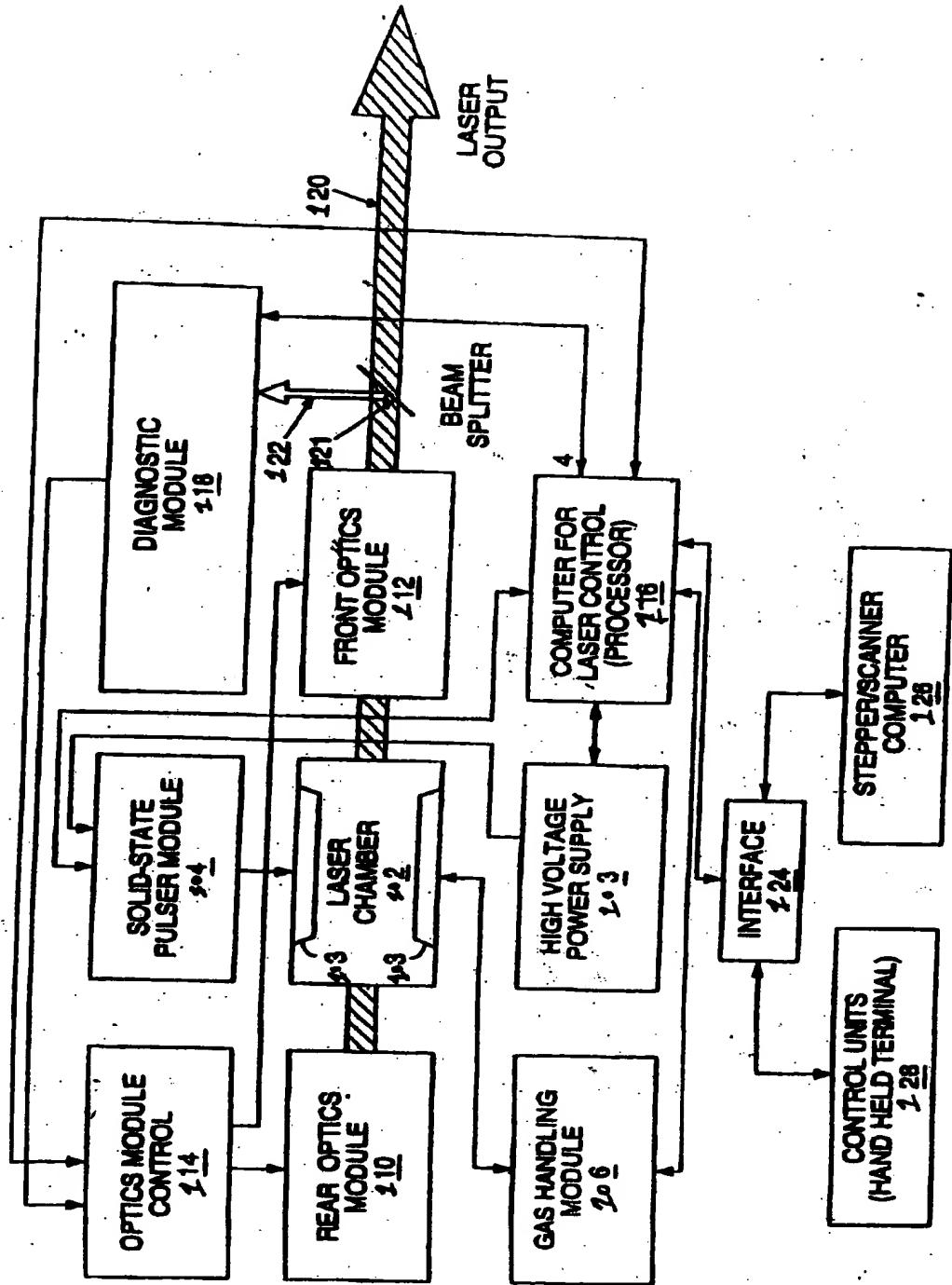
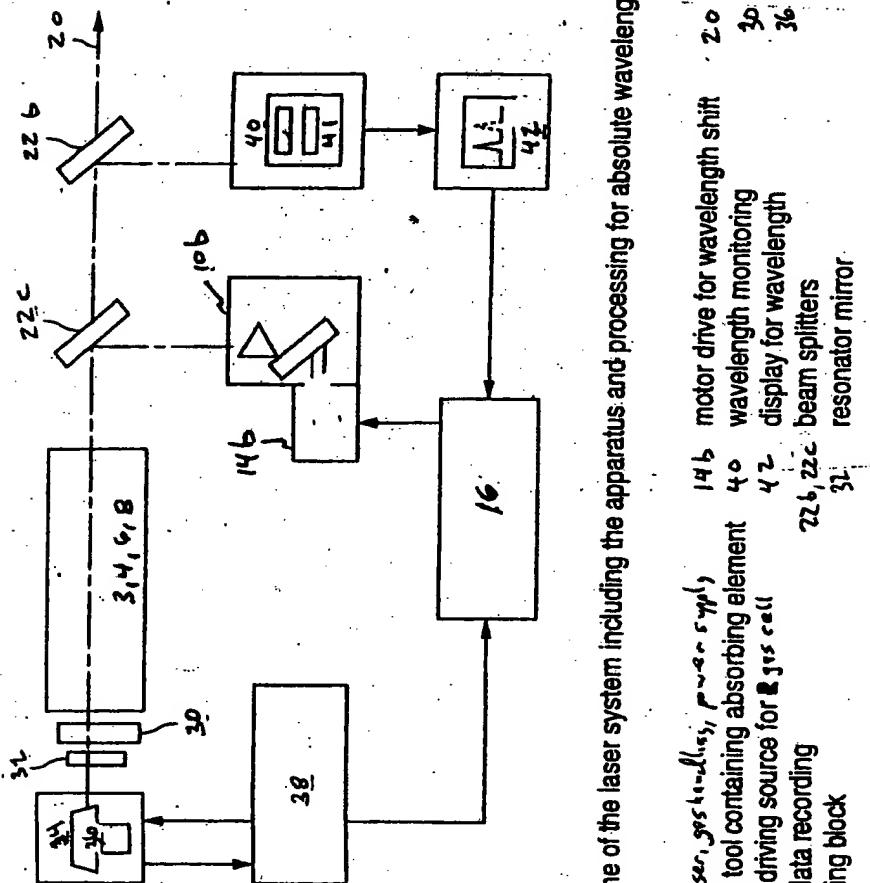


Figure 1



Scheme of the laser system including the apparatus and processing for absolute wavelength calibration

- 31, 41, 61, 81 laser chamber, Resonator containing a gas cell
- 34 wavelength calibration tool containing absorbing element
- 38 signal processing and driving source for gas cell
- 16 main processing and data recording
- 10b line narrowing and tuning block
- 20 narrow-band output beam
- 40 polarizer
- 42 gaseous element
- 22b, 22c resonator mirror
- 31

FIG. 2

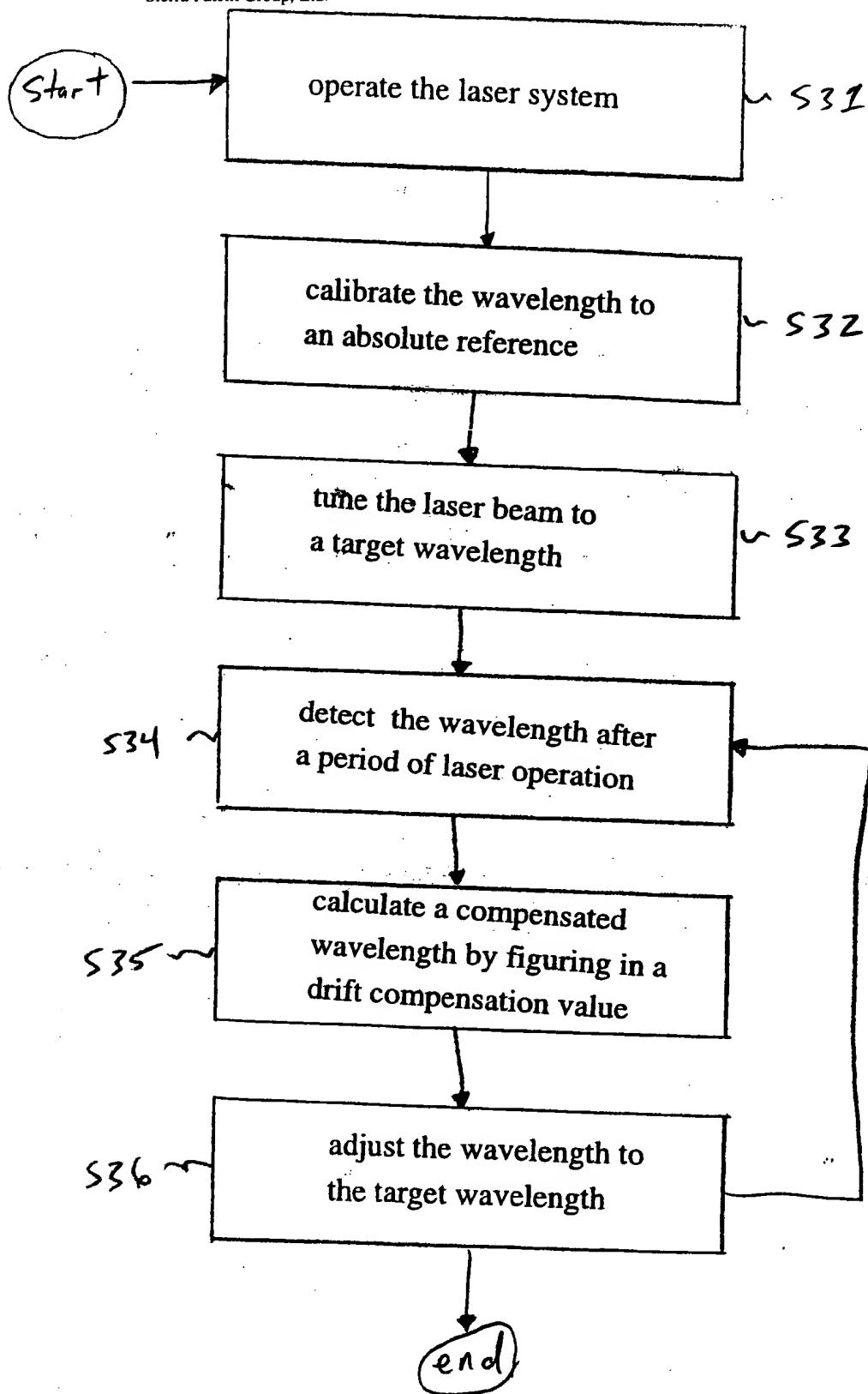


Figure 3

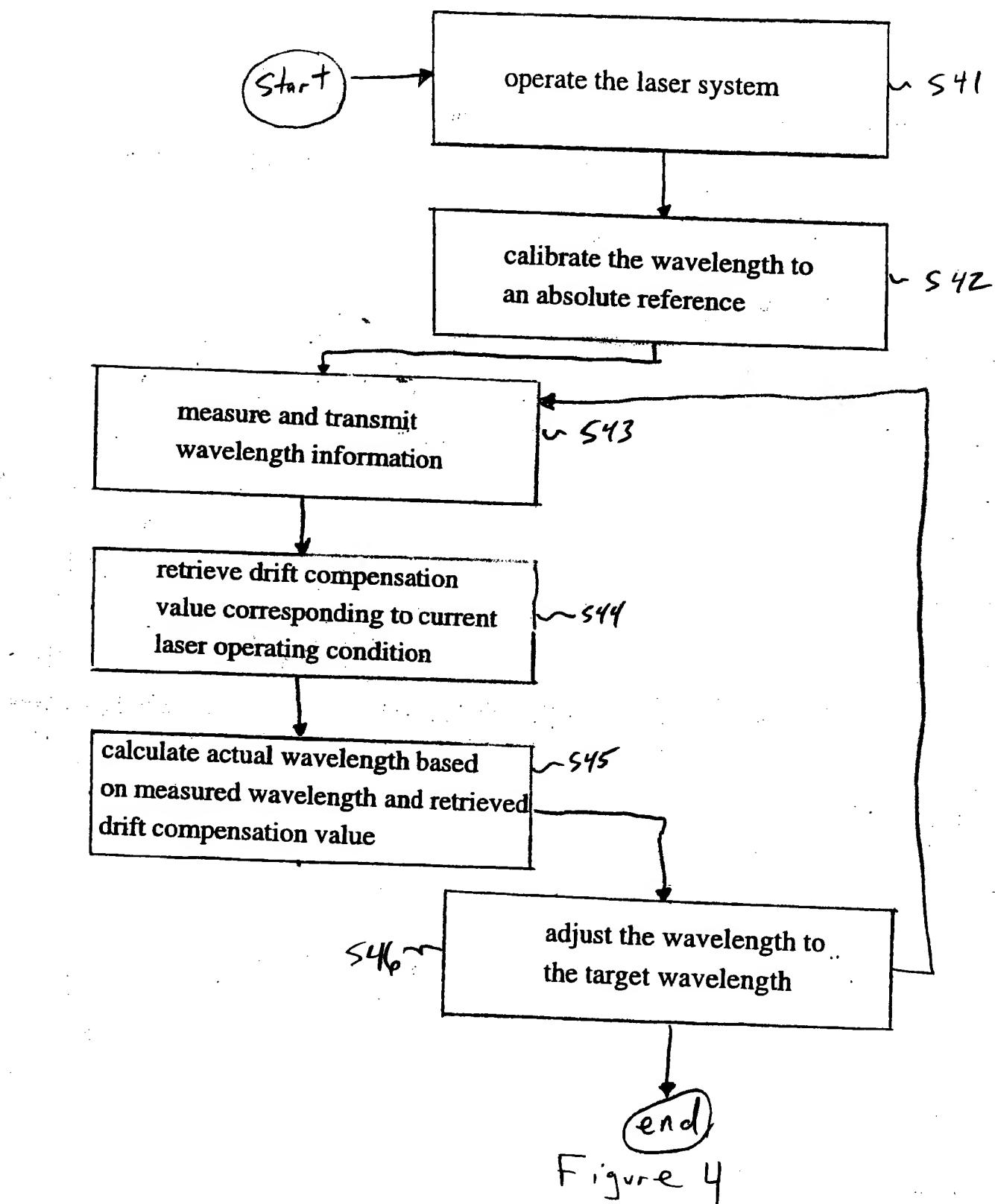


Figure 4

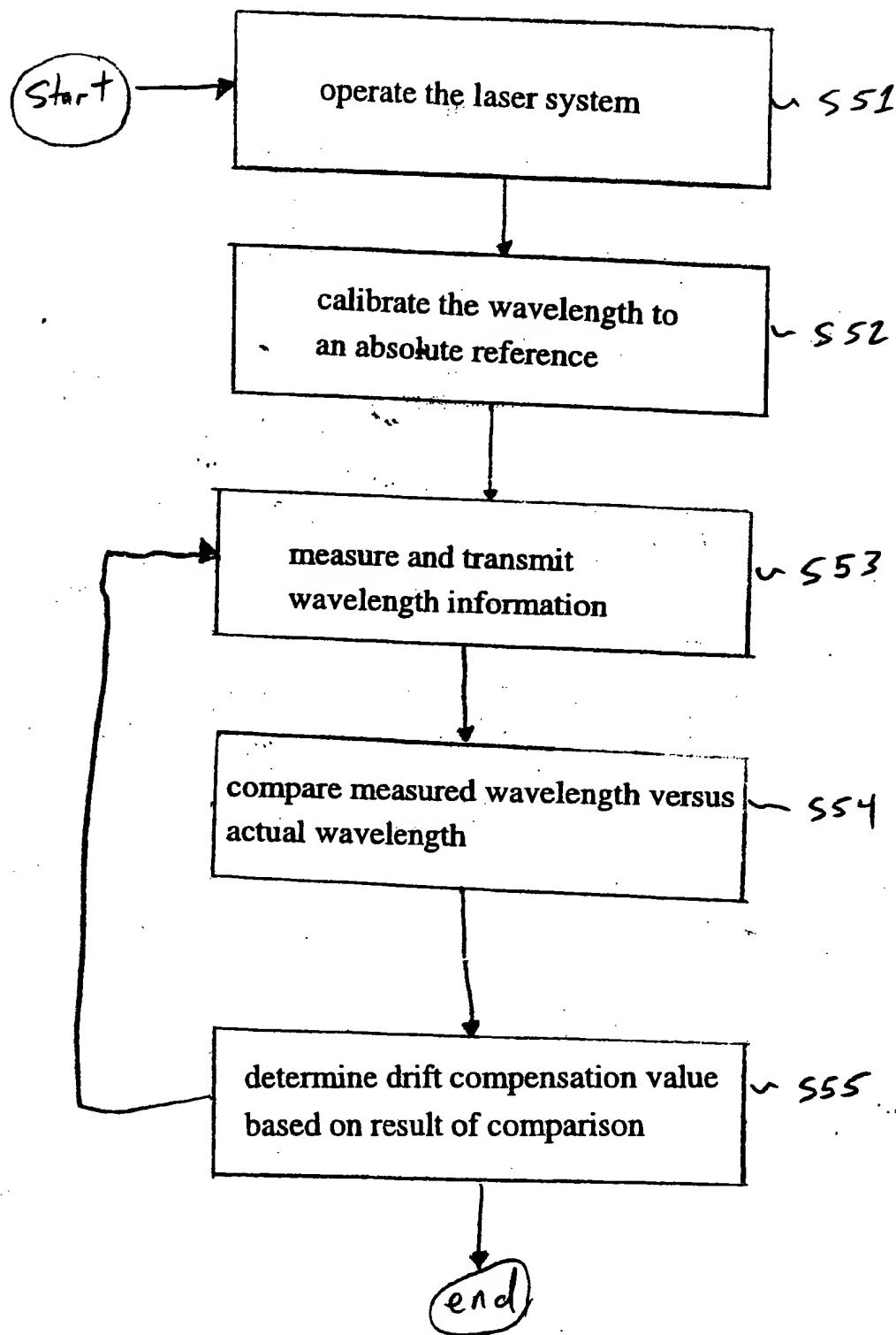


Figure 5

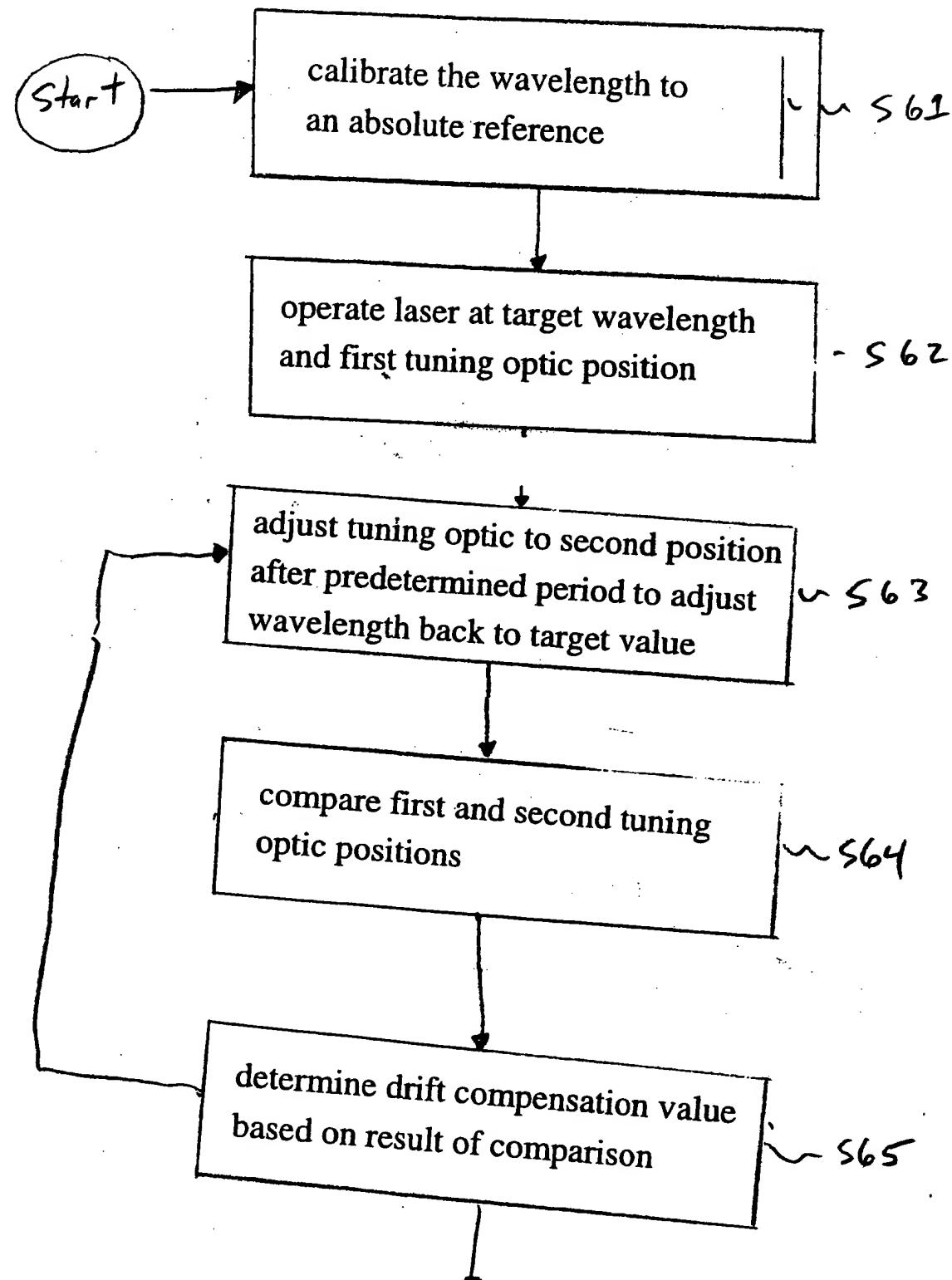


Figure 6

Express Mail: ET1610

S Filed: July 10, 2001

Inventors: Albrecht, et

Title: Precise Monitor Etalon Calibration Technique

Docket No.: LMPY-12910 (273/U)

Attorney: Andrew V. Smith

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Sierra Patent Group, Ltd.

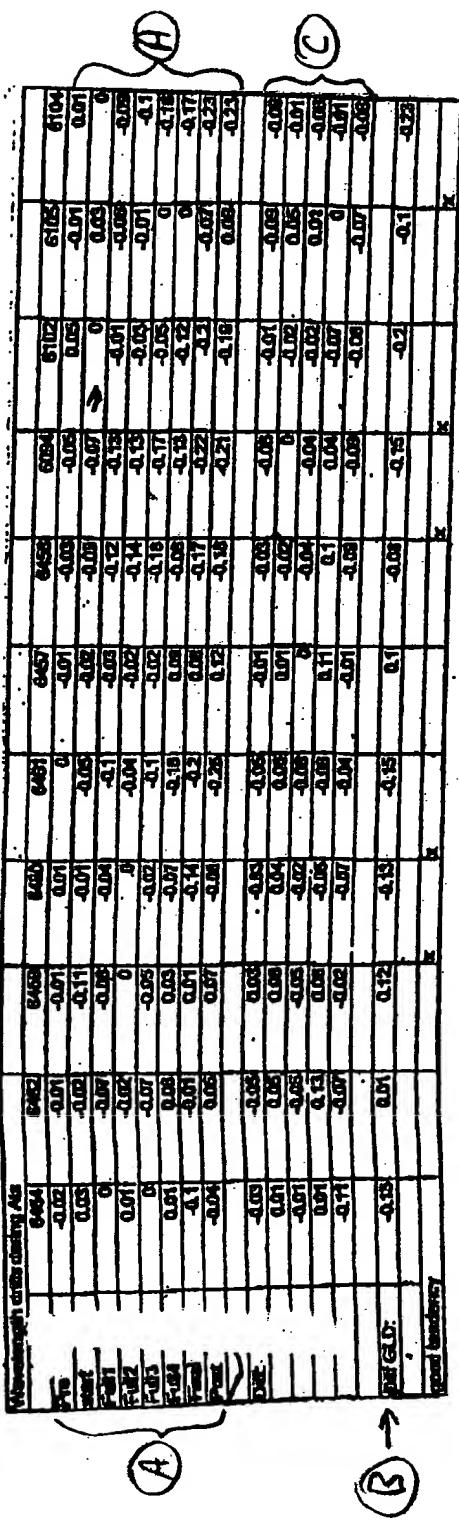


Figure 7